

## Ph.D Defense

# Low power transistors and Quantum Physics based on

## Low Dimensional Materials

#### Fan Chen

Network for Computational Nanotechnology, (NCN) Department of Physics and Astronomy, Purdue University, USA

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Motivation	<ul> <li>Why Tunnel FETs based on 2D materials</li> </ul>	
Method	<ul> <li>Non-equilibrium, Open Boundary Simulator NEMO5</li> </ul>	
Bilayer Graphene	<ul> <li>Experimental Benchmark</li> <li>Electrostatically Doped Tunnel FET proposal</li> </ul>	
Interlayer TFETs	<ul> <li>Model Assumptions and Validation</li> <li>MoS2-WTe2 interlayer Tunnel FET Device physics &amp;Performance</li> </ul>	e
Black Phosphorous	<ul> <li>Thickness Engineered Tunnel FET proposal</li> </ul>	
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#### Challenges for Modern Electronics: Power Consumption

#### More transistors, but not faster processors









# NEMØ5

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#### Fundamental limitation of MOSFETs









#### Major Challenge in TFETs







High ON needs Small Eg, small m\*, shorter tunnel distance  $\lambda$ 







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#### Thin Channel has Smaller Tunnel Distance



#### Thin Channel has smaller tunnel distance $\lambda \rightarrow$ High ON





#### **2D Material Reduces Tunnel Distance**



2D Material reduces tunnel distance  $\lambda$ 















#### **Closed and Open systems**

#### Closed Equilibrium

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#### Open Boundary Non-Equilibrium

- 1. Injection S from contacts
- 2. Open Boundry
- 3. Channel is out of equilibrium



Transport in device requires non-equilibrium, open boundary Method





### Non-equilibrium Open Boundary Method

#### Closed Equilibrium

 $E\psi = H\psi$ 

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#### Open Boundary Non-Equilibrium

 $(E - H - \Sigma \downarrow 1 - \Sigma \downarrow 2)\psi = S$ 



Non-equilibrium, Open boundary Method Capture the required Physics





#### Self Consistent calculation



self-consistent calculation is performed for electrostatics





#### Hamiltonian based on atoms



The material parameters need to be obtained.





#### **Device Modeling Simulator: NEMO5**

















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#### Choice of channel material for homojunction TFET



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#### Bilayer Graphene: Tunable Eg







Bilayer Graphene TFET: Small Achievable Eg, Small effective mass





#### Bilayer Graphene double gate FET Simulation and Experiment



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#### IV Shifting in Bilayer Graphene Double Gate FET



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#### Electrical Doped Bilayer Graphene Junction



#### Electrical Doping in bilayer graphene creates tunnel junction





Configurable post after fabrication between pin and nip

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No dopant states within bandgap  $\rightarrow$  good OFF-state performance



# NEMØ5

#### Bilayer Graphene TFET: ON and SS



SS<10mv/dec

10<sup>-2</sup>

 $I_{DS}(\mu A/\mu m)$ 

10<sup>0</sup>

 $10^{2}$ 



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#### **Configurable Electrostatically Doped High Performance Bilayer Graphene Tunnel FET**

FAN W. CHEN<sup>1</sup>, HESAMEDDIN ILATIKHAMENEH<sup>2</sup>, GERHARD KLIMECK<sup>2</sup> (Fellow, IEEE), ZHIHONG CHEN<sup>3</sup>, AND RAJIB RAHMAN<sup>2</sup>

#### BLG TFET can operate at 0.1V with 100uA/um ON current





100

80

60

40

20

10<sup>-4</sup>

SS (mV/dec)





## Summary Evaluation of Bilayer Graphene TFET

Device	$\begin{array}{c c} V_1 & V_g & V_2 \\ \hline S & Bilayer Graphene & HfO2 \\ \hline V_1' & (V_g - 2) & V_2' \end{array}$	
VDD (V)	0.1	
ION (uA/um)	100	
SS (mV/dec)	8	
Energy Delay Product	Energy↓ Delay ↓	
Scalability	90nm	
Comments	Difficult Gate Alignment	
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m

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#### Further Reduce Tunnel Distance: Heterojunction TFET

 $I \downarrow ON \uparrow \rightarrow Trans \uparrow \rightarrow \lambda \downarrow \rightarrow t \downarrow ch \downarrow$  $Trans \propto \exp(-\lambda \cdot \sqrt{m} \uparrow \ast \cdot E \not g)$ TMD **Chemical formula: MX**<sub>2</sub> **Black phosphorus** MoS<sub>2</sub>, WSe<sub>2</sub> н He en.wikipedia.org  $MX_2$ M = Transition metal X = Chalcogen Li Be В С N 0 F Ne 3 12 AI Si Ρ S CI Ar Na Mg 10 11 Various materials v Κ Ca Sc Ti Cr Mn Fe Co Ni Cu Zn Ga Ge As Se Br Kr (MoS2, WTe2, WSe2 ..) Eg: 1.0eV → 2.5eV Rb Sr Y Zr Nb Mo Tc Ru Rh Pd Ag Cd In Sn Sb Те Xe Hf Та Os Hg TI Pb Bi At Rn Cs Ba La - Lu W Re Au Po FI Fr Ra Ac - Lr Rf Db Sg Bh Hs Mt Ds Rg Cn Uut Uup Lv Uus Uuo Nature Chemistry 5, 263-275 (2013) en.wikipedia.org Eg Various TMD materials are available for heterojunction TFET

 $\rightarrow$  Further reduce  $\lambda$ 

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### 2D material interlayer TFET advantages



#### Surface promises low density of interface defects

Tunnel distance  $\lambda$ , is the sub-nanometer interlayer distance









MoS2-WTe2 combination is chosen for broken band alignment



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Assumption I : different layer has been strained to the same lattice constant to be registered

Assumption II : Interface VdW coupling is the average of the VdW of the two materials



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#### Tight binding compared with DFT







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#### Gr/BN/Gr vertical tunneling



Gr/BN/Gr structure is simulated in order to Validate Model





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#### Gr/BN/Gr: NEMO5 Current value matches experiment









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semiconductor heterojunctions

FTTER

Kai Tak Lam, Gyungseon Seol, and Jing Guo

#### A device switching Mechanism that is commonly believed

#### **Applied Physics** Letters

#### JOURNAL OF APPLIED PHYSICS 115, 074508 (2014)



#### Single particle transport in two-dimensional heterojunction interlayer tunneling field effect transistor

Mingda (Oscar) Li,<sup>1,a)</sup> David Esseni,<sup>2</sup> Gregory Snider,<sup>1</sup> Debdeep Jena,<sup>1</sup> and Huili Grace Xing<sup>1,b)</sup> <sup>1</sup>University of Notre Dame, Notre Dame, Indiana 46556, USA <sup>2</sup>University of Udine, Udine, Italy

IEEE TRANSACTIONS ON ELECTRON DEVICES, VOL. 63, NO. 11, NOVEMBER 2016

08 (2014)

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#### doi:10.1038/nature15387

#### A subthermionic tunnel field-effect transistor with an atomically thin channel

Operating principles of vertical transistors based on mo

Deblina Sarkar<sup>1</sup>, Xuejun Xie<sup>1</sup>, Wei Liu<sup>1</sup>, Wei Cao<sup>1</sup>, Jiahao Kang<sup>1</sup>, Yongji Gong<sup>2</sup>, Stephan Kraemer<sup>3</sup>, Pulickel M. Ajayan<sup>2</sup> & Kaustav Banerjee



Jiang Cao, Student Member, IEEE, Demetrio Logoteta, Sibel Özkaya, Blanca Biel, Alessandro Cresti, Marco G. Pala, Member, IEEE, and David Esseni, Fellow, IEEE



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Interlayer TFET Bands Shifting Switching Mechanism: OFF

Bands Shifting Switching Mechanism



Source

Bot. Gate













Extension regions is defined as the region that has only one layer





#### The importance of extension region: OFF current and SS



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ON and SS are degraded with shorter extension region



 $V_{DS}$ 

#### The importance of Extension Region Position Resolved Carrier Density



Both Top and Bottom Layer stay charged at the OFF state; Long extension region blocks the leakage current.

NEM@



#### The importance of extension region: band diagram & current



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#### MoS2-WTe2 Interlayer TFET: Decrease in top layer charge



Decrease in top layer charge is due to current fllowing





#### MoS2-WTe2 Interlayer TFET: Total Charge





Though Device stays highly charged, total Charge is not huge due to neutralization









#### MoS2-WTe2 Interlayer TFET: Energy Delay Product



MoS2-WTe2 interlayer TFETs does not show too much improvement in EDP







#### Evaluation of MoS2-WTe2 interlayer TFET

Device	S $V_1$ Bilayer Graphene $V_2$ HIO2 $V_2$ HIO2 HIO2 HIO2 HIO2	V <sub>TG</sub> Top Gate WTe2 MoS2 Bot. Gate U V <sub>BG</sub>
VDD (V)	0.1	0.3
ION (uA/um)	100	1000
SS (mV/dec)	8	10
Energy Delay Product	Energy↓ Delay ↓	Energy↓ Delay ↑
Scalability	90nm	15nm
Comments	Difficult Gate Alignment	Device Switching Mechanism
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Interlayer TFETs	<ul> <li>Gr/hBN/Gr Matching Experiments → Validates Model</li> <li>MoS2-WTe2 interlayer TFET → Low Energy, Large Delay Different Switching Mechanism</li> </ul>	
Black Phosphorous	<ul> <li>Thickness Engineered Tunnel FET proposal</li> </ul>	









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Black Phosphorous	• Thickness Engineered Tunnel FET proposal	
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#### Further Reduce Tunnel Distance: Heterojunction TFET

Eg



#### 2D Material Reduces tunnel distance $\boldsymbol{\lambda}$





#### One Common Problem of Heterojunction Tunnel FET





#### Heterojunction from Thickness Dependent Materials

 $I \downarrow ON \uparrow \rightarrow Trans \uparrow \rightarrow \lambda \downarrow \rightarrow t \downarrow ch \downarrow$ 

 $Trans \propto \exp(-\lambda \cdot \sqrt{m} \uparrow \ast \cdot E / g)$ 



Using thickness dependent Eg to create an heterojunction TFET







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#### Thickness Engineered TFET Performance



**TE-TFET** has a better ON, SS compared to homo-junction





#### TE-TFET Working Principle



Thickness Engineered TFET → TE-TFET

1.5 1.5 Phosphorene TFET ON ON 1 Band Edges [eV] 0.5 [ 0 0.5 -0.5 -0.5 -1 0.5 TE-TFET 11 0 Efs -0.5 Efd -1 -1.5 -1.5 Phosphorene TFET  $10^{-6} 10^{-4} 10^{-2} 10^{0} 10^{2} 10^{4}$ 20 15 10 5 0 Current [ $\mu$ A/ $\mu$ m] Transport [nm] 0.5 0.5 Phosphorene TFET OFF OFF 0 0-0.5 -0.5 -1 Efs Efd 3L -3L TE-TFET TE-TFET -1.5 -1.5 Phosphorene TFET  $20 \ 10^{-6} \ 10^{-4} \ 10^{-2} \ 10^{0} \ 10^{2} \ 10^{4}$ 5 10 15 0 Current [ $\mu$ A/ $\mu$ m] Transport [nm]

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- ON: small tunnel distance
- OFF: Large tunnel Barrier

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#### **TE-TFET** device scaling



A scalability to 9nm channel length with constant field scaling





#### TE-TFET: Energy-Delay Product



#### Thickness Engineered TFET → TE-TFET

Energy-Delay not much improvement compared to homo-junction BP TFET

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## Evaluation of TE-TFET based on phosphorene & Summary

Device	S $V_1$ Bilayer Graphene $V_2$ Hf02 $V_2$ Hf02 $V_2$ $V_$	V <sub>TG</sub> Top Gate WTe2 UG343434333333333333333333333333333333 MoS2 Bot. Gate UVBG	P Top Oxide N V <sub>DS</sub> Source Bot. Oxide Drain
VDD (V)	0.1	0.3	0.4
ION (uA/um)	100	1000	1000
SS (mV/dec)	8	10	15
Energy Delay Product	Energy↓ Delay ↓	Energy↓ Delay ↑	Energy↓ Delay ↓
Scalability	90nm	15nm	9nm
Comments	Difficult Gate Alignment	Device Switching Mechanism	Not much improved than homo BP, Difficult to fabricate
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### Agenda (Finished)

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Black Phosphorous	<ul> <li>Pro: Scale down to 9nm, Low Energy, Small Delay</li> <li>Con: Not much improvement compared to homo BP TFET, but more difficult to fabricate</li> </ul>	
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Tillmann Kubis



Hesameddin Ilatikhameneh



Archana Tankasala



Tan



Luis Jauregui



Thank you for your attention









## Thank you!







